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CONFIRMATION NO. 5218 Bib Data Sheet FILING DATE **ATTORNEY GROUP ART UNIT** CLASS **SERIAL NUMBER** DOCKET NO. 11/21/2001 2873 09/997.484 359 S004-4470 RULE APPLICANTS Manabu Oumi, Chiba-shi, JAPAN; Susumu Ichihara, Chiba-shi, JAPAN; Kenji Kato, Chiba-shi, JAPAN; Yasuyuki Mitsuoka, Chiba-shi, JAPAN; Takashi Niwa, Chiba-shi, JAPAN; Nobuyuki Kasama, Chiba-shi, JAPAN; Hidetaka Maeda, Chiba-shi, JAPAN; Yoko Shinohara, Chiba-shi, JAPAN; ** CONTINUING DATA **************** * FOREIGN APPLICATIONS ************ JAPAN 2000-355972 11/22/2000 JAPAN 2000-367560 12/01/2000 JAPAN 2000-373307 12/07/2000 JAPAN 2000-377253 12/12/2000 JAPAN 2000-377254 12/12/2000 IF REQUIRED, FOREIGN FILING LICENSE GRANTED * 12/17/2001 Foreign Priority claimed TOTAL INDEPENDENT SHEETS STATE OR 35 USC 119 (a-d) conditions CLAIMS **CLAIMS** COUNTRY DRAWING JAPAN 24 3 32 Verified and Acknowledged **ADDRESS** ADAMS & WILKS 50 Broadway, 31st Floor New York, NY 10004 TITLE Method of fabricating optical aperture and method of fabricating probe for near field light device All Fees 1.16 Fees (Filing) FEES: Authority has been given in Paper ☐ 1.17 Fees (Processing Ext. of **FILING FEE** No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: RECEIVED time) 942 1.18 Fees (Issue)

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